

Contents

LIST OF CONTRIBUTORS	vii
FOREWORD	ix
PREFACE	xi
CONTENTS OF PART B	xvii

Numerical Methods for Computing Electrostatic and Magnetic Fields

P. BONJOUR

I. Introduction	1
II. Electrostatic Lenses	2
III. Magnetostatics of Vacuum and Media	5
IV. Discretization of Laplace's and Poisson's Equations and Generation of the Mesh	13
V. Difference Equations	18
VI. Solution of the Set of Difference Equations	36
VII. Results	41
References	43

Methods of Computing Optical Properties and Combating Aberrations for Low-Intensity Beams

P. W. HAWKES

I. Introduction	45
II. Numerical Methods of Solving Equations of Motion	47
III. Aberration Coefficient Structure	60
IV. Optimization and Partial Correction of Aberrations	90
V. Concluding Remarks	140
References	143

Emittance and Brightness: Definitions and Measurements

CLAUDE LEJEUNE AND JEAN AUBERT

I. Introduction	159
II. Definitions and Basic Properties	164
III. Measurement of Emittance and Brightness	201
IV. Conclusion	249
Symbols and Conventions	252
References	254

High-Resolution Scanning Transmission Low-Energy Ion Microscopes and Microanalyzers

RICCARDO LEVI-SETTI

I. Introduction	261
II. Formation of a Microprobe in the Nanometer Range	263
III. Sources of High Specific Brightness	270
IV. The Design of Optical Systems for SIM and STIM: Aberrations	289
V. Results with Operating Systems	299
VI. Future Developments	315
References	318
Note Added in Proof	320

High-Energy Ion Microprobes

BERND MARTIN AND RAINER NOBILING

I. Surface Analysis by High-Energy Ions	321
II. Optical Systems for Ions in the Megaelectron-Volt Energy Range	324
III. Selected Findings	341
IV. Future Developments	344
References	345

INDEX	349
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